Far-Infrared Spectroscopy of Thin Oxide Films

C.P. Weber¹, J.W. Orenstein^{1,2}, and Michael C. Martin³

¹Materials Science Division, Ernest Orlando Lawrence Berkeley National Laboratory,
University of California, Berkeley, California 94720, USA

²Department of Physics, University of California, Berkeley, California 94720, USA

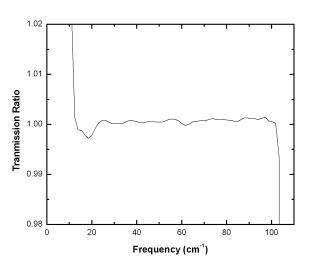
³Advanced Light Source Division, Ernest Orlando Lawrence Berkeley National Laboratory,
University of California, Berkeley, California 94720, USA

INTRODUCTION

Our work at beamline 1.4.2 has involved the setting-up and use of Fourier-transform infrared (FTIR) spectroscopy in the range of $20\text{-}100~\text{cm}^{-1}$ to complement lower-frequency time-domain Terrahertz (TD-THz) studies of thin films of the oxides $SrRuO_3$ and $Bi_2Sr_2CaCu_2O_{8+\delta}$. We have demonstrated stable measurement in the desired frequency range, have characterized the optical properties of the $NdGaO_3$ and $LaAlO_3$ substrates on which the two films, respectively, were grown, and have obtained transmission data for $SrRuO_3$ which upon further analysis may help to illuminate the oxide's non-Fermi-liquid electrical properties.

SYSTEM CAPABILITIES

The largest portion of our work at beamline 1.4.2 this year has been the adaptation of the beamline's Bruker IFS 66v/S FTIR system to the configuration necessary for far-infrared measurements of thin films. We installed, aligned, and calibrated a Janis cold-finger cryostat, on which the thin-film samples are mounted for measurement. This cryostat allows us to control the samples' temperatures in the range of approximately 9 K to 300 K. We aligned the special beamsplitters (Mylar of thickness 23 μm and 50 μm) necessary for far-IR measurements, installed a power supply, and tested the operation of an Infrared Laboratories bolometer, a LHe-cooled infrared detector with an optical low-pass filter at 100 cm⁻¹. We found that the system provides data with an excellent signal-to-noise ratio for frequencies of 20-100 cm⁻¹; see figure 1. Moreover, a single beamsplitter (23 μ) provides data over the entire range, so that a sample's far-

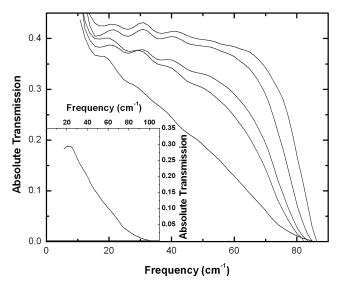


IR transmission can be determined in one experiment.

Figure 1: Measurement stability. The curve shown is the ratio of two consecutive sets of data, each collected for approximately 1 minute, with the source and external conditions held constant. The smallness of the deviations from unity shows excellent measurement stability in the range 20-100 cm⁻¹. The deviation below that range arises from opacity of the beamsplitter, and that above arises from a low-pass filter.

CHARACTERIZATION OF SUBSTRATES

Because thin films are grown on substrates, the optical transmission of a film must be normalized by that of the substrate. We measured the absolute transmission of the NdGaO₃ and LaAlO₃ substrates on which the SrRuO₃ and Bi₂Sr₂CaCu₂O_{8+ δ} films, respectively, were grown; the results



appear in figure 2. We found that both substrates are opaque at frequencies above ~100 cm⁻¹; measurement using an unfiltered detector showed that this opacity is intrinsic to the substrates, and not an artifact of the bolometer's low-pass filter. This opacity limits the possible bandwidth of optical measurements of films grown on these substrates.

Figure 2: Infrared transmission of NdGaO₃ **substrate**. From top to bottom: T = 9 K, 65 K, 110K, 150 K, 300 K. The curves for T < 300 K were fit to the form of the transmission arising from a single-oscillator absorption at approximately 90 cm^{-1} , as described in the text. **Inset**: The transmission of the LaAlO₃ substrate at T = 300 K is shaped similarly to that of NdGaO₃. The transmission of LaAlO₃ rises above 1000 cm^{-1} (not shown).

Our measurements of a film yield the ratio, T, of the transmission of the film-substrate complex to that of the substrate alone; we seek to fit the measured T to that arising from a theoretical form for the complex electrical conductivity, σ , of the film. In the thin-film approximation, for a substrate of index of refraction n, T is given by:

$$T = |(n+1)/(n+1+\sigma dZ)|^2$$

where d is the thickness of the substrate, and Z is 377 Ω . In order to perform the desired fit both the real and imaginary parts of n must be known, but both cannot be determined from measurements of optical transmission over a finite frequency range. However, we found that the measured transmission of NdGaO₃ (fig. 2) fits well to the form arising from a single-oscillator absorption at approximately 90 cm⁻¹, particularly for the lower temperatures; only the width of the oscillator was found to vary with temperature. We thus calculated the full complex n from the single-oscillator model.

CHARACTERIZATION OF SrRuO₃ FILMS

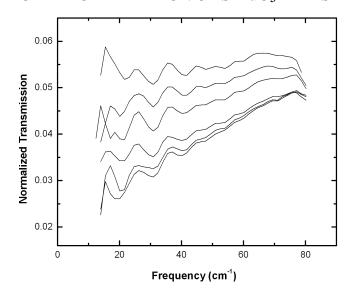


Figure 3: Infrared transmission of SrRuO₃ film, normalized by the transmission of the substrate. From top to bottom: T = 65 K, 55 K, 45 K, 35 K, 25 K, 9 K. These curves are being fit to a form arising from non-fermi-liquid conductivity (see text). It is expected that the temperature dependence of the infrared transmission will reflect the temperature dependence of the inverse scattering rate, τ , which was determined by TD-THz methods.

The electrical properties of SrRuO₃ have attracted attention [1,2] because of the material's magnetic properties [3,4], and because of its similarities to the cuprate high-T_c superconductors. Recent measurements in the range 100-1000 cm⁻¹

[1] suggest non-Fermi-liquid electrical behavior, a behavior also thought to exist in the cuprates. We have measured the transmission of $SrRuO_3$ films at various temperatures; some of these data appear in figure 3. We are in the process of fitting these curves to a form for the transmission which arises from non-Fermi-liquid conductivity, σ , suggested by Ioffe and Millis [5].

A critical aspect of this fitting process is the connection with TD-THz data taken at lower frequencies. The inverse scattering rate τ , a parameter of the electrical conductivity, is given by $\tau = (d/d\omega) \, (\sigma_i/\sigma_r)$, where ω is the frequency, and σ_r and σ_i are the real and imaginary parts of σ , respectively. Since TD-THz measurements yield both σ_r and σ_i , our collaborators [6] have been able to accurately determine τ for temperatures below 70 K. It is expected that the temperature dependence of τ will be consistent with the temperature dependence of our far-infrared data in a non-Fermi-liquid model of the conductivity.

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Principal investigator: Joseph Orenstein, Material Science Division, Ernest Orlando Lawrence Berkeley National Laboratory and Department of Physics, University of California, Berkeley. Email: JWOrenstein@lbl.gov. Telephone: 510-486-5880.